

PATENT ABSTRACTS OF JAPAN

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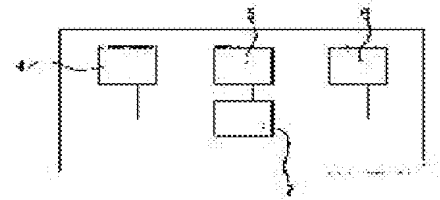
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(54) APPARATUS AND SYSTEM FOR MANAGING MANUFACTURE OF SEMICONDUCTOR DEVICE

(57)Abstract:

PROBLEM TO BE SOLVED: To provide an apparatus for managing manufacture of a semiconductor device which can reliably judge the device by judging the semiconductor manufacture management on the basis of the number of defects in the device.

SOLUTION: The apparatus includes a means 4 for detecting the number of defects on a wafer as a defect number, a means 5 for detecting the number of defective ones of chips on the wafer as a defective chip number T, a means 6 for setting a plurality of predetermined regions on the basis of a reference defective chip number T and a reference defect number H as preset references with respect to wafer productivity, and a means 7 for judging that a relationship between the defect number and defective chip number is included in either one of the regions preset by the region setting means 6 to judge acceptance or rejection of the wafer.



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